

IN THE SPECIFICATION

Please replace the second paragraph on Page 9, lines 13-17, with the following amended paragraph:

-- The detection unit 40 is composed of a spectrograph 42 and a light measuring device array 44. The spectrograph 42 splits the light reflected from the surface of the sample of the substrate 30 based on the degree of each wavelength, and the split light is inputted into the optical measuring device array 44, thereby measuring a light intensity at each wavelength. --

Please replace the second paragraph on Page 10, lines 6-10, with the following amended paragraph:

-- Preferably, the measurement of the film thickness performed by the computation unit 52 and the analyzing unit 42 54 is implemented using a computer. The computer receives a spectrum data with respect to each wavelength from the spectrograph 42 and the light device array 44 and computes the thickness of the thin film and stores a data related to the thickness of the thin film. --